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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

OCT 22 2004
PATENT & TRADEMARK OFFICE

In re Application of: Christopher HERTZLER, et al.) Confirmation No.: 4676
 Serial No.: 09/846,495)
 Filing Date: April 30, 2001) Examiner: Hien Thi TRAN
)
) Art Unit: 1764

For: TREATMENT SYSTEM FOR REMOVING HAZARDOUS SUBSTANCES FROM A SEMICONDUCTOR PROCESS WASTE GAS STREAM

AMENDMENT AND RESPONSE TRANSMITTAL

Mail Stop Amendment
 Commissioner for Patents
 P. O. Box 1450
 Alexandria, VA 22313-1450

Dear Sir:

Transmitted herewith is an Amendment in the above identified application.

No additional fee is required.
 Also attached: Postcard.

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	Fee
Total Claims	22	22	0	\$18.00 =	\$0.00
Independent Claims	4	4	0	\$88.00 =	\$0.00
Multiple claims newly presented					\$0.00
Fee for extension of time					\$0.00
TOTAL FEE DUE					\$0.00

The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 50-1302, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

HICKMAN PALERMO TRUONG & BECKER LLP

John D. Henkhaus
 John D. Henkhaus, Registration No. 42,656

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450

on 10/18/04 by Darci Sakamoto
 Darci Sakamoto

1600 Willow Street
 San Jose, CA 95125
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AMENDMENT UNDER 37 C.F.R. § 1.111

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RESPONSE TO OFFICE ACTION

Sir:

This is in response to the Office Action mailed September 24, 2004, the shortened statutory period for which runs until October 24, 2004. Please revise the subject application as indicated below.

Remarks begin on page 2 of this paper.